

M Bulut CoÅkun

List of Publications by Year in descending order

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26
papers

552
citations

759233

12
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996975

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26
all docs

26
docs citations

26
times ranked

1008
citing authors

#	ARTICLE	IF	CITATIONS
1	Ultrafast Dynamic Piezoresistive Response of Graphene-Based Cellular Elastomers. <i>Advanced Materials</i> , 2016, 28, 194-200.	21.0	171
2	Vibrating membrane with discontinuities for rapid and efficient microfluidic mixing. <i>Lab on A Chip</i> , 2015, 15, 4206-4216.	6.0	68
3	Ultrasensitive Strain Sensor Produced by Direct Patterning of Liquid Crystals of Graphene Oxide on a Flexible Substrate. <i>ACS Applied Materials & Interfaces</i> , 2016, 8, 22501-22505.	8.0	52
4	Detecting Subtle Vibrations Using Graphene-Based Cellular Elastomers. <i>ACS Applied Materials & Interfaces</i> , 2017, 9, 11345-11349.	8.0	32
5	An adjustable-stiffness MEMS force sensor: Design, characterization, and control. <i>Mechatronics</i> , 2018, 56, 198-210.	3.3	30
6	On-Chip Feedthrough Cancellation Methods for Microfabricated AFM Cantilevers With Integrated Piezoelectric Transducers. <i>Journal of Microelectromechanical Systems</i> , 2017, 26, 1287-1297.	2.5	25
7	Nanoscale displacement sensing using microfabricated variable-inductance planar coils. <i>Applied Physics Letters</i> , 2013, 103, 143501.	3.3	24
8	Control of an Active AFM Cantilever With Differential Sensing Configuration. <i>IEEE Transactions on Control Systems Technology</i> , 2019, 27, 2271-2278.	5.2	23
9	Feedback-Controlled MEMS Force Sensor for Characterization of Microcantilevers. <i>Journal of Microelectromechanical Systems</i> , 2015, 24, 1092-1101.	2.5	19
10	Friction and Wear Characteristics of Haynes 25, 188, and 214 Superalloys Against Hastelloy X up to 540°C. <i>Tribology Letters</i> , 2012, 45, 497-503.	2.6	18
11	Zero displacement microelectromechanical force sensor using feedback control. <i>Applied Physics Letters</i> , 2014, 104, 153502.	3.3	18
12	High Dynamic Range AFM Cantilever With a Collocated Piezoelectric Actuator-Sensor Pair. <i>Journal of Microelectromechanical Systems</i> , 2020, 29, 260-267.	2.5	13
13	A microfabricated fringing field capacitive pH sensor with an integrated readout circuit. <i>Applied Physics Letters</i> , 2014, 104, .	3.3	11
14	A high bandwidth microelectromechanical system-based nanopositioner for scanning tunneling microscopy. <i>Review of Scientific Instruments</i> , 2019, 90, 073706.	1.3	8
15	Design, Fabrication, and Characterization of a Piezoelectric AFM Cantilever Array. , 2019, , .		8
16	A High Dynamic Range AFM Probe with Collocated Piezoelectric Transducer Pairs. , 2020, , .		6
17	A MEMS capacitive pH sensor for high acidic and basic solutions. , 2014, , .		5
18	Design, Fabrication and Characterization of Active Atomic Force Microscope Cantilever Arrays. , 2021, , .		5

#	ARTICLE	IF	CITATIONS
19	A MEMS Nanopositioner With Integrated Tip for Scanning Tunneling Microscopy. Journal of Microelectromechanical Systems, 2021, 30, 271-280.	2.5	5
20	Q control of a microfabricated piezoelectric cantilever with on-chip feedthrough cancellation. , 2017, , .		4
21	FPGA-Based Characterization and Q-Control of an Active AFM Cantilever. , 2020, , .		4
22	A Fully Coupled 3D Finite Element Analysis for a Bump-Type Compliant Foil Bearing. , 2011, , .		3
23	Force-compensating MEMS sensor for AFM cantilever stiffness calibration. , 2014, , .		0
24	Frequency Tunable Surface Acoustic Wave Actuators for Adjustable Pitch Diffraction Grating. Journal of Microelectromechanical Systems, 2020, 29, 699-705.	2.5	0
25	Active Microcantilevers for Dynamic Mode Atomic Force Microscopy. , 2021, , .		0
26	Friction and Wear Characteristics of H25, H188, H214 Against Hastelloy X. , 2011, , .		0